

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

IN RE APPLICATION OF: Masashi GOTO, et al.

SERIAL NO: New Application

GAU:

FILED: Herewith

EXAMINER:

FOR: FILM-FORMING METHOD, METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE,  
SEMICONDUCTOR DEVICE, METHOD OF MANUFACTURING DISPLAY DEVICE, AND DISPLAY DEVICE

**INFORMATION DISCLOSURE STATEMENT UNDER 37 CFR 1.97**

COMMISSIONER FOR PATENTS  
ALEXANDRIA, VIRGINIA 22313

SIR:

Applicant(s) wish to disclose the following information.

**REFERENCES**

- The applicant(s) wish to make of record the references listed on the attached form PTO-1449. Copies of the listed references are attached, where required, as are either statements of relevancy or any readily available English translations of pertinent portions of any non-English language references.
- A check or credit card payment form is attached in the amount required under 37 CFR §1.17(p).

**RELATED CASES**

- Attached is a list of applicant's pending application(s) or issued patent(s) which may be related to the present application. A copy of the patent(s), together with a copy of the claims and drawings of the pending application(s) is attached along with PTO 1449.
- A check or credit card payment form is attached in the amount required under 37 CFR §1.17(p).

**CERTIFICATION**

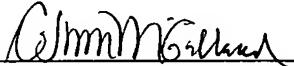
- Each item of information contained in this information disclosure statement was first cited in any communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this statement.
- No item of information contained in this information disclosure statement was cited in a communication from a foreign patent office in a counterpart foreign application or, to the knowledge of the undersigned, having made reasonable inquiry, was known to any individual designated in 37 CFR §1.56(c) more than three months prior to the filing of this statement.

**DEPOSIT ACCOUNT**

- Please charge any additional fees for the papers being filed herewith and for which no check or credit card payment is enclosed herewith, or credit any overpayment to deposit account number 15-0030. A duplicate copy of this sheet is enclosed.

Respectfully submitted,

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**STATEMENT OF RELEVANCY**

**References AO (11-279773), AW, and AX of Form PTO-1449:**

These documents are disclosed in the body of the specification.

Form PTO 1449 (Modified)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY DOCKET NO. 251602US2		SERIAL NO. New Application	
LIST OF REFERENCES CITED BY APPLICANT		APPLICANT		Masashi GOTO, et al.			
		FILING DATE		GROUP			
Herewith							
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
	AL						
	AM						
	AN						
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION		
	AO	11-279773	10/12/99	Japan	YES	NO	X
	AP						
	AQ						
	AR						
	AS						
	AT						
	AU						
	AV						
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)							
	AW	M. GOTO, et al., "SURFACE WAVE PLASMA OXIDATION AT LOW TEMPERATURE FOR GATE INSULATOR OF POLY-Si TFTs", Proceedings of The Ninth International Display Workshops, December 4-6, 2002, pgs. 355 - 358.					
	AX	Reiji MORIOKA, et al., "DEPOSITION OF HIGH- $\kappa$ ZIRCONIUM OXIDES IN VHF PLASMA-ENHANCED CVD USING METAL-ORGANIC PRECURSOR", Collection of Lecture Documents of the "20 <sup>th</sup> Plasma Processing Research Meeting" sponsored by Plasma Electronics Branch of Applied Physics Institute, January 29, 2003, pgs. 317 - 318.					
	AY						
	AZ					<input type="checkbox"/> Additional References sheet(s) attached	
Examiner					Date Considered		
*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							